of the support areas being movable between the second chamber and a third one of the chambers, the two support areas being disposed on the substrate support in spaced relation, wherein the first support area and the second support area are respectively located in different ones of the three chambers when the support is in the final position.

In Claim 4, line 2, please replace "had" with -- has --.

11. (Amended) A substrate load lock comprising:

a frame forming at least one sealable chamber;

means for varying the environment of the chamber; and

at least two substrate supports movably connected to the frame so that each substrate support is alternately movable into the sealable chamber;

the two substrate supports being connected to each other wherein movement of one substrate support effects movement of the other substrate support, and wherein, when the sealable chamber is sealed, only one of the substrate supports is located therein.

In Claim 21, line 8, after "reciprocates", please replace "to alternately move" with -- for alternately moving --.

In Claim 21, line 10, please replace "begin" with -- being --.

26. (Amended) A method for transporting a substrate between a substrate processing device and a supply module comprising the steps of:

transporting the substrate between a movable first substrate support area in a load lock and the supply module, the first substrate support area being located in an initial position wherein a first substrate transport mechanism for transporting substrates between the supply module and load lock has access to the first substrate support area;

moving the first substrate support area within the load lock from an initial position to a final position, wherein in the final position a second substrate transport mechanism has access to the first substrate support area; and

transporting the substrate with the second substrate transport mechanism between the first substrate support area in the load lock and the substrate processing device;

wherein moving the first substrate support area effects movement of a second substrate support area of the load lock.

In Claim 27, ~~line~~ 2, before "second", please replace "a" with -- the --.

28. (Amended) A method for transporting a substrate as in Claim 27, [wherein] further comprising the step of providing the load lock with the first substrate support area and the second substrate support area [are] being connected to a common support movably mounted to the load lock.

Please add ~~the~~ following Claims:

-- 30. A substrate load lock comprising:

a frame forming at least three chambers; and

a substrate support movably mounted to the frame, the substrate support having at least two separate support areas, a first one of the support areas being movable between a first one of the chambers and a second one of the chambers, and a second one of the support areas being movable between the second chamber and a third one of the chambers;

wherein the substrate support has three seal members thereon located so that the first seal member and the second seal member seal the second chamber when the first support area is in the second chamber, and the second seal member and the third seal member seal the second chamber when the second support area is in the second chamber.

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31. A substrate load lock comprising:

a frame forming at least one sealable chamber;

means for varying the environment of the chamber; and

at least two substrate supports movably connected to the frame so that each substrate support is alternately movable into the sealable chamber;

wherein, the two substrate supports are moved by a common actuator mounted to the frame, and wherein, when the sealable chamber is sealed, only one of the substrate supports is located therein.

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